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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **NAKATA, Yoshihiro et al.**

Group Art Unit: **1771**

Serial No.: **10/807,174**

Examiner: **Hai VO**

Filed: **March 24, 2004**

P.T.O. Confirmation No.: 4205

**FOR: SILICON-BASED COMPOSITION, LOW DIELECTRIC CONSTANT FILM,
SEMICONDUCTOR DEVICE, AND METHOD FOR PRODUCING LOW
DIELECTRIC CONSTANT FILM**

RESPONSE UNDER 37 CFR §1.116

MAILSTOP AF

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

June 30, 2006

Sir:

In response to the Office Action dated **March 31, 2006**, please amend the above-identified application as follows: